AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (Currently Amended) A magnetic recording medium, comprising:
 - an elongate non-magnetic substrate;
- a foundation layer formed by a vacuum thin-film forming technique on over said non-magnetic substrate;
- a magnetic layer having a thickness of 55 nm or less formed by a vacuum thin film forming technique -on over said non-magnetic substrate such that the magnetic layer does not include a non-magnetic binder, wherein
- a signal is reproduced by sliding one of a magneto-resistive head and a giant magneto-resistive head, and

said foundation layer is formed of a silicon nitride film having a thickness of 2 nm to 50 nm.

- 2. (Currently Amended) A magnetic recording medium, comprising:
 - an elongate non-magnetic substrate;
- a magnetic layer having a thickness of 55 nm or less formed by a vacuum thin film evaporation technique -on- over one principal surface of said non-magnetic substrate such that the magnetic layer does not include a non-magnetic binder; and
- a back foundation layer formed by a vacuum thin-film forming technique on over a principal surface of said non-magnetic substrate on a side opposite said magnetic layer, wherein
- a signal is reproduced by sliding one of a magneto-resistive head and a giant magneto-resistive head, and

said back foundation layer is formed of a silicon nitride film.

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3. (Original) The magnetic recording medium according to claim 2, wherein said back foundation layer is formed of a silicon nitride film having a thickness of 2 nm to 200 nm.

4. (Currently Amended) The magnetic recording medium according to claim 2, wherein said back foundation layer and a back coating layer are formed in layers —on—over_said principal surface of said non-magnetic substrate on the side opposite the side on which said magnetic layer is formed.